

CLAIMS SET AS AMENDED

1. (Currently Amended) A method of forming a liquid crystal layer on a substrate having a sealed pattern, comprising:

preparing a liquid crystal material in a projecting portion having a nozzle plate containing a plurality of orifices;

applying a vibration and pressure to the projecting portion so as to emit the liquid crystal material simultaneously from the plurality of orifices projecting portion;

moving the substrate in one direction; and

depositing the ~~emitted~~ liquid crystal material emitted simultaneously from the plurality of orifices uniformly onto the substrate during the movement of the substrate in the one direction; and applying a voltage to the projecting portion to adjust the volume of the emitted liquid crystal material ~~adjusting an on-off of a voltage~~ according to a position of the moving substrate.

2. (Currently Amended) The method according to claim 1, wherein ~~the projecting portion has a nozzle plate containing a plurality of orifices~~, said nozzle plate ~~adjusting~~ adjusts the applied pressure for emitting the liquid crystal material, ~~said liquid crystal material being emitted through the plurality of orifices~~.

3. (Cancelled)

4. (Original) The method according to claim 1, wherein the liquid crystal material is emitted and deposited in a vacuum chamber.

5. (Original) The method according to claim 1, wherein the vibration is generated by a voltage applied to a resonator.

6. (Original) The method according to claim 5, wherein the generated vibration is transmitted to the projecting portion through a resonating plate.

7. (Original) The method according to claim 1, wherein the substrate has a black matrix under the sealed pattern.

8. (Original) The method according to claim 7, wherein the liquid crystal material start and stop is deposited on the black matrix.

9. (Currently Amended) An apparatus for forming a liquid crystal layer on a substrate having a seal pattern, comprising:

a projecting portion having a nozzle plate containing a plurality of orifices
~~for~~ simultaneously emitting a liquid crystal material;

a resonator for generating a vibration;

a resonating plate located between the resonator and the projecting portion for transmitting the vibration to the projecting portion; and

a stage for moving the substrate in one direction during continuously emitting of the liquid crystal material simultaneously from the projecting portion

uniformly onto the substrate wherein ~~an on-off of~~ a voltage is applied to the resonator to adjust the volume of the emitted liquid crystal material and ~~applied to said apparatus is adjusted~~ according to a position of the moving substrate.

10. (Currently Amended) The apparatus according to claim 9, wherein ~~the projecting portion has a nozzle plate containing a plurality of orifices, the nozzle plate adjusting~~ adjusts the applied pressure for emitting the liquid crystal material, ~~the liquid crystal material being emitted through said plurality of orifices.~~

11. (Cancelled)

12. (Previously Presented) The apparatus according to claim 9, wherein means are provided for moving the stage.

13. (Original) The apparatus according to claim 9, further comprising a vacuum chamber for encompassing the projecting portion, the resonator and the resonating plate.

14. (Currently Amended) The apparatus method ~~method~~ according to claim 9, wherein voltage means are provided for generating vibration in the resonator.

15. (New) The method according to claim 1, wherein an on-off of a voltage is adjusted according to a position of the moving substrate.

16. (New) The apparatus of claim 9, wherein means are provided for adjusting an on-off of a voltage according to a position of the moving substrate.